
Contents

PREFACE TO THE PAPERBACK EDITION	v
PREFACE	vi
ACKNOWLEDGEMENTS	viii
CONTENTS	xi
CHAPTER 1. THE POLARIZATION OF LIGHT WAVES	1
1.1. The concept of polarization	1
1.2. Polychromatic and monochromatic waves of light	2
1.3. Polarization of monochromatic waves of arbitrary spatial structure	2
1.3.1. Elliptical polarization	6
1.3.2. Linear and circular polarizations	9
1.4. The phasor (complex) representation of time-harmonic fields	10
1.5. Uniform TE plane waves of light	11
1.6. The Jones vector of a uniform TE plane wave	13
1.6.1. Wave intensity	16
1.6.2. Jones vectors of some states of polarization	17
1.6.3. Orthogonal and orthonormal pairs of Jones vectors	19
1.6.4. Transformation of the Jones vector under the effect of a coordinate rotation	19
1.6.5. Basis Jones vectors and basis states of polarization	22
1.6.5.1. Cartesian basis vectors	22
1.6.5.2. Circular basis vectors	22
1.6.5.3. Arbitrary basis vectors	25
1.6.6. The Cartesian and circular Jones vectors of a given elliptical polarization state	26
1.7. Representation of the polarization states of light by complex numbers	28
1.7.1. The Cartesian complex-plane representation of polarized light	28
1.7.1.1. Orthogonal states	30
1.7.1.2. Equi-azimuth and equi-ellipticity contours	33

1.7.2. The circular complex-plane representation of polarized light	39
1.7.3. The generalized complex-plane representation of polarized light	43
1.8. The Poincaré-sphere representation of polarized light	47
1.9. The polarization of quasi-monochromatic waves	52
1.9.1. The Jones vector of a quasi-monochromatic wave	53
1.9.2. The Stokes parameters and the Stokes vector	55
1.9.3. The coherency-matrix representation	60
 CHAPTER 2. PROPAGATION OF POLARIZED LIGHT THROUGH POLARIZING OPTICAL SYSTEMS	66
2.1. Polarizing optical systems	66
2.2. The Jones-matrix formulation	67
2.2.1. The significance of the elements T_{ij} of the Jones matrix	69
2.2.2. Cascade of optical systems	70
2.2.3. Jones matrices of basic optical devices	72
2.2.3.1. Transmission-type devices	72
2.2.3.2. Reflection-type devices	77
2.2.4. Transformation of the Cartesian Jones matrix under the effect of a coordinate rotation	79
2.2.5. Circular and generalized Jones matrices	81
2.3. Separability of information on the ellipse of polarization in the Jones-matrix formulation—The polarization transfer function	84
2.4. Transformation of the ellipse of polarization by an optical system in the complex-plane representation	85
2.5. Transformation of polarization by an optical system in the Poincaré-sphere representation	92
2.6. Separability of information on amplitude and phase in the Jones-matrix formulation—The amplitude and phase transfer functions	94
2.6.1. The eigenvalue problem—General classification of optical devices	97
2.6.1.1. Elliptic retarders	98
2.6.1.2. Elliptic partial polarizers	100
2.6.1.3. Elliptic ideal polarizers	101
2.6.1.4. Other devices	102
2.7. Polarization-dependent intensity transmittance of optical systems	103
2.7.1. Loci of polarization states of equal attenuation or amplification	103
2.7.2. Simplified expressions for the intensity transmittance	107
2.7.3. Generalization of the Law of Malus	110
2.7.4. Special cases of optical systems	111
2.8. Resolution of an arbitrary polarization state into two given orthogonal states in the complex-plane representation	113
2.8.1. Nearness of two polarization states in the complex-plane representation	113

2.8.2. Resolution of an arbitrary polarization state into two given orthogonal states in the Poincaré-sphere representation	116
2.9. Polarization-dependent phase shift introduced by an optical system	117
2.10. Propagation of polarized light in anisotropic media	119
2.10.1. Evolution of the ellipse of polarization	122
2.10.1.1. The case of homogeneous anisotropic media	123
2.10.1.2. The case of inhomogeneous anisotropic media	131
2.10.2. Evolution of the complex amplitude	137
2.11. Propagation of partially polarized quasi-monochromatic light through non-depolarizing optical systems—The coherency-matrix formulation	141
2.11.1. Intensity transmittance of a linear non-depolarizing optical system for partially polarized incident light	144
2.12. Propagation of partially polarized quasi-monochromatic light through depolarizing optical systems—The Mueller-matrix formulation	148

CHAPTER 3. THEORY AND ANALYSIS OF MEASUREMENTS IN ELLIPSOMETER SYSTEMS	153
3.1. Introduction	153
3.2. Ellipsometric measurement of the Jones matrix of an optical system—The basis of generalized ellipsometry	156
3.3. Ellipsometry on optical systems with known eigenpolarizations	158
3.4. Ellipsometric measurement of the ratio of eigenvalues of an optical system with orthogonal linear eigenpolarizations	159
3.4.1. Null ellipsometry	166
3.4.2. The fixed-compensator-azimuth nulling scheme with $C = \pm \frac{1}{4}\pi$, $\delta_C = -\frac{1}{2}\pi$ and $T_C = 1$	167
3.4.3. Alternate ellipsometer arrangement with the compensator placed after the optical system	169
3.4.4. The ratio of eigenvalues ρ_S in reflection and transmission ellipsometry	173
3.4.5. Unified treatment of the PCSA and PSCA ellipsometer arrangements—Example of the application of the bilinear polarization transfer function	175
3.5. Ellipsometric measurement of the ratio of eigenvalues of an optical system with orthogonal circular eigenpolarizations	180
3.6. Ellipsometric measurement of the ratio of eigenvalues of an optical system with elliptic eigenpolarizations	184
3.7. Effect of azimuth-angle errors and component imperfections on the ellipsometric measurement of ρ_S	186
3.7.1. The imperfection plate of a non-ideal optical component	189
3.7.2. Transposition of two optical components	191
3.7.3. The PCWSW'A ellipsometer arrangement	192

3.7.3.1. Azimuth-angle errors	193
3.7.3.2. Component imperfections	195
3.7.3.3. Errors in the ellipsometric angles ψ and Δ	202
3.7.3.4. Two-zone averages	208
3.7.3.5. Four-zone averages	210
3.7.3.6. Choice of compensator azimuth and position	211
3.8. Ellipsometry with imperfect components including incoherent effects	213
3.8.1. Application to the PCWSW'A ellipsometer arrangement	216
3.8.1.1. Polarizer and analyzer imperfections	219
3.8.1.2. Compensator imperfection	224
3.8.1.3. Entrance-window, system, and exit-window imperfections	225
3.8.2. Zone averaging	226
3.8.3. Component depolarization	229
3.8.4. Discussion	231
3.9. Generalized ellipsometry	233
3.9.1. The polarizer-compensator combination as a controlled polarization filter	234
3.9.2. Nulling schemes and conditions of compensation	238
3.9.2.1. The fixed-analyzer nulling scheme	239
3.9.2.2. The fixed-compensator nulling scheme	240
3.9.2.3. The fixed-polarizer nulling scheme	242
3.9.3. Multiple-null measurements	245
3.9.4. Alternate PCSA ellipsometer arrangement	246
3.10. Other ellipsometer arrangements	247
3.10.1. Null ellipsometers that do not employ compensators	248
3.10.1.1. An ellipsometer based on the detection of the azimuth of the polarization ellipse only, with no measurement of ellipticity	248
3.10.1.2. Self-compensated ellipsometers based on the angle-of-incidence tunability of the reflection phase difference Δ	251
3.10.2. Photometric ellipsometers	255
3.10.2.1. Static photometric ellipsometers	256
3.10.2.2. Dynamic photometric ellipsometers	257
3.10.3. Interferometric Ellipsometers (IE)	262
3.11. Modulated ellipsometry	265
3.11.1. PSA arrangement	266
3.11.2. PCSA arrangement	267
CHAPTER 4. REFLECTION AND TRANSMISSION OF POLARIZED LIGHT BY STRATIFIED PLANAR STRUCTURES	269
4.1. Introduction	269

4.2.	Reflection and refraction at the planar interface between two isotropic media	270
4.3.	Reflection and transmission by an ambient-film-substrate system	283
4.4.	The equations of reflection and transmission ellipsometry for ambient-film-substrate systems	288
4.4.1.	Reflection ellipsometry	288
4.4.1.1.	Constant-Angle-of-Incidence Contours (CAIC) of the ellipsometric function $\rho(\phi, d)$	289
4.4.1.2.	Constant-Thickness Contours (CTC) of the ellipsometric function $\rho(\phi, d)$	293
4.4.1.3.	Cartesian curves	298
4.4.2.	Transmission ellipsometry	299
4.4.3.	Linear approximation of the equations of reflection and transmission ellipsometry for ambient-film-substrate systems	301
4.4.3.1.	Reflection	301
4.4.3.2.	Transmission	304
4.4.3.3.	ψ and Δ sensitivity factors	305
4.4.3.4.	Validity of the linear approximations	312
4.5.	Numerical inversion of the exact equation of reflection ellipsometry	315
4.5.1.	Cases that allow analytical inversion	315
4.5.2.	General formulation of the numerical-inversion problem and choice of error function	317
4.5.3.	Multiple-Angle-of-Incidence (MAI) ellipsometry	320
4.5.3.1.	Independence (or interdependence) of the MAI system of equations: The parameter correlation test	321
4.5.3.2.	The Hessian matrix and rate of convergence	324
4.5.3.3.	The air– SiO_2 –Si system – An example	326
4.6.	Reflection and transmission by isotropic stratified planar structures	332
4.7.	Reflection and transmission by anisotropic stratified planar structures	340
4.7.1.	Reflection and transmission by a finite anisotropic layer between semi-infinite isotropic ambient and substrate media	348
4.7.2.	Reflection and transmission by a semi-infinite anisotropic substrate in an isotropic ambient	352
4.7.3.	Explicit expressions for the reflection matrix in simple special cases	354
4.7.3.1.	Isotropic ambient and uniaxially anisotropic substrate	354
4.7.3.2.	Isotropic ambient and biaxially anisotropic substrate	355
4.7.3.3.	Uniaxially anisotropic film on an isotropic substrate in an isotropic ambient	356
4.7.3.4.	Biaxially anisotropic film on an isotropic substrate in an isotropic ambient	357
4.7.3.5.	Uniaxial film on a uniaxial substrate in an isotropic ambient	358
4.8.	Ellipsometry on surfaces covered with discontinuous films and on surfaces with rough boundaries	359

CHAPTER 5. INSTRUMENTATION AND TECHNIQUES OF ELLIPSOMETRY	364
5.1. Introduction	364
5.2. The basic instrument—The null ellipsometer	364
5.2.1. The optical devices	366
5.2.1.1. Linear polarizers	367
5.2.1.2. Retarders	370
5.2.1.3. Other polarizing optical devices	372
5.2.2. Optical components of an ellipsometer that perform no polarizing function	373
5.2.3. Light sources and detectors	375
5.3. Operation of the null ellipsometer	376
5.3.1. Alignment of the telescopes	376
5.3.2. Calibration of the ellipsometer divided circles	380
5.3.3. Nulling schemes	385
5.4. Sources of error and their correction	386
5.4.1. Azimuth-angle errors, component and cell-window imperfections	388
5.4.2. Measurement of ellipsometer imperfection parameters	389
5.4.3. Beam deviation errors	392
5.4.4. Effect of auto-collimated parasitic beams from multiple reflections	397
5.4.5. Errors that arise from certain assumptions concerning the ellipsometer light beam	398
5.4.5.1. Bandwidth	398
5.4.5.2. Source polarization and component depolarization	398
5.4.5.3. Collimation and non-uniform polarization	400
5.4.6. Polarization-dependent photodetector sensitivity	401
5.4.7. Residual mechanical imperfections	402
5.4.8. Other errors	402
5.4.9. Model errors	402
5.5. Precision of null ellipsometers	403
5.6. Automation of null ellipsometers	405
5.6.1. Motor-driven self-nulled ellipsometers	406
5.6.2. Electro-optic self-nulled ellipsometers	408
5.7. Automatic photometric ellipsometers	411
5.7.1. The rotating-analyzer ellipsometer	411
5.7.2. The polarization-modulated ellipsometer	415
CHAPTER 6. APPLICATIONS OF ELLIPSOMETRY	417
6.1. Introduction	417
6.2. Optical properties of materials and spectroscopic ellipsometry	417
6.2.1. Optical properties of materials in bulk phase	417
6.2.2. Optical properties of materials in thin-film phase	428

6.3. Physical and chemical adsorption	433
6.4. Oxidation of semiconductor and metal surfaces	443
6.5. Electrochemistry	452
6.6. Applications of ellipsometry in biology and medicine	464
6.6.1. Interaction of blood with foreign surfaces – Blood coagulation	465
6.6.2. Antigen-antibody immunological reactions in thin films	466
6.6.3. The immunoelectroadsorption test	468
6.6.4. Measurement of cell-surface (coat) materials	469
6.7. Other applications of ellipsometry	473
 APPENDIX	487
REFERENCES	493
LISTINGS OF THE CONTENTS OF THE INTERNATIONAL ELLIPSOMETRY CONFERENCES	501
AUTHOR INDEX	517
SUBJECT INDEX	522